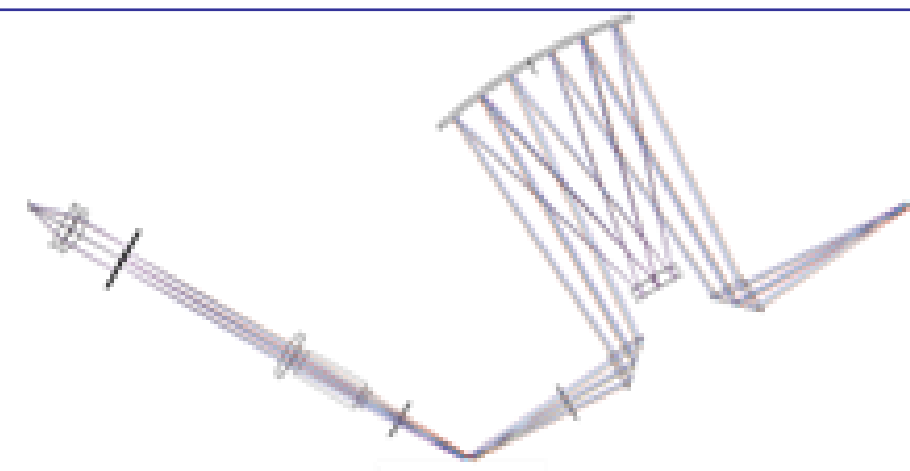
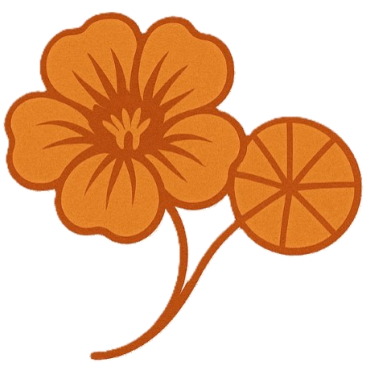




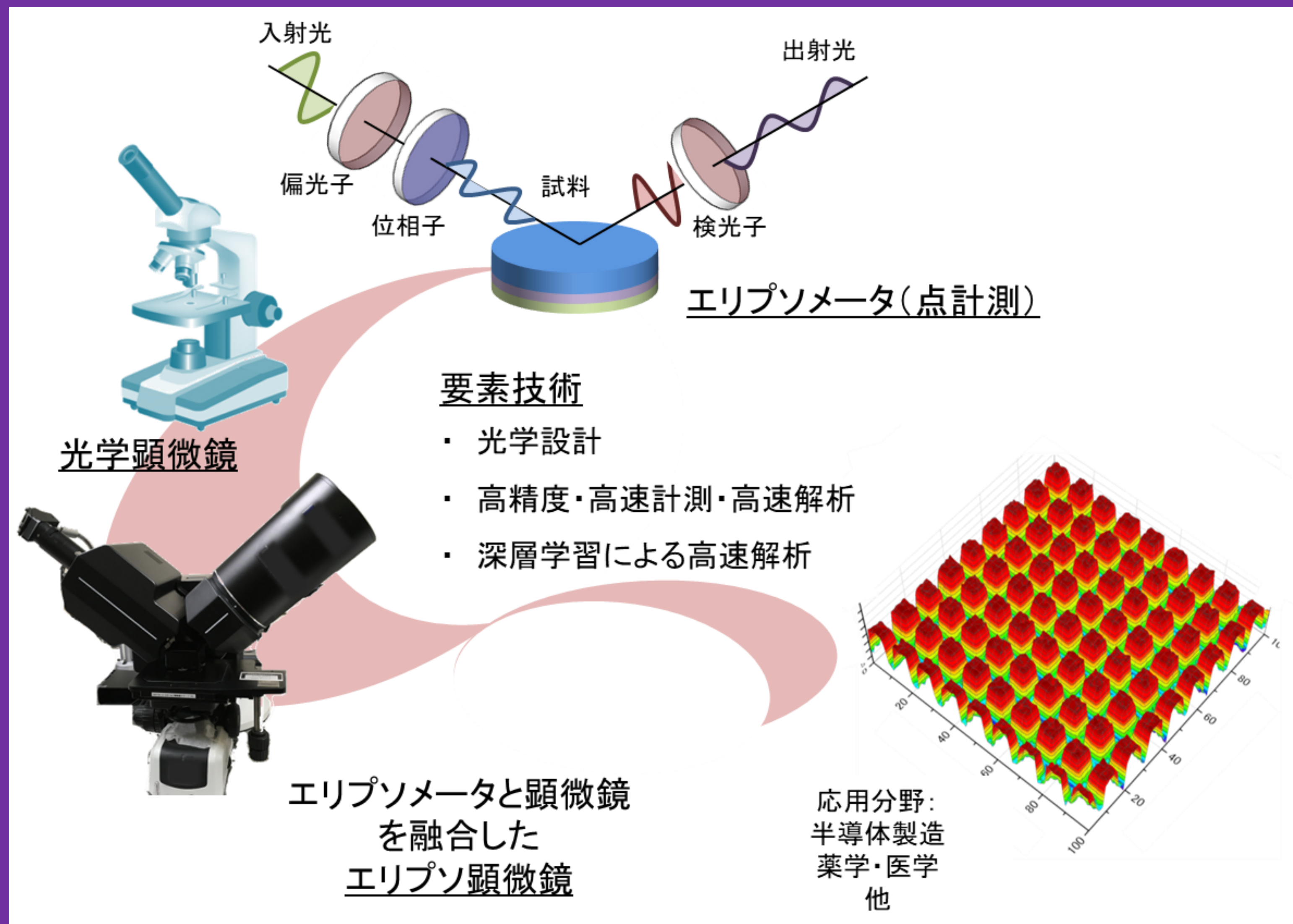
金 蓮花
(山梨大学 工学部)

【今後の展開 商品イメージ応用できる分野】

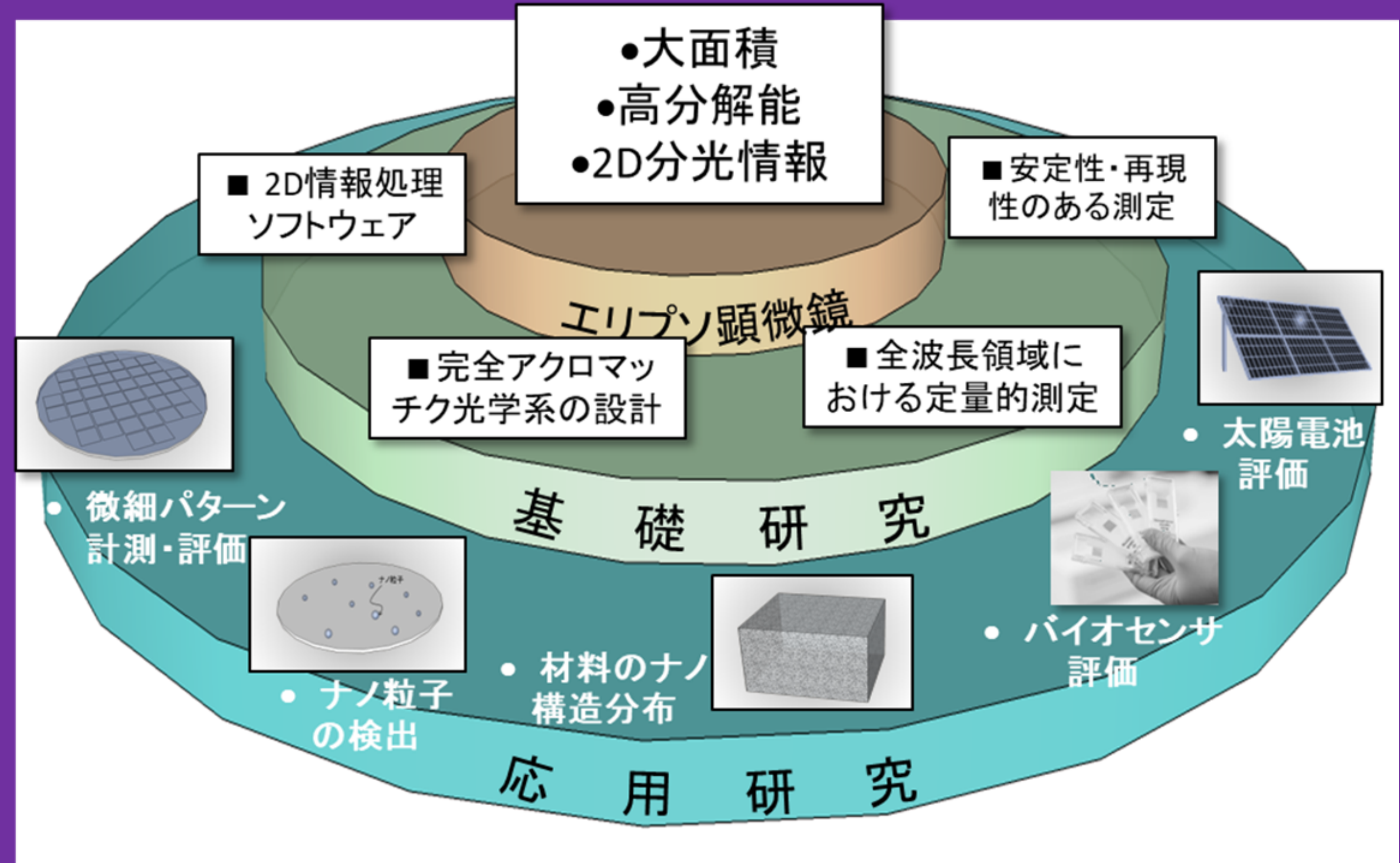
半導体製造分野（前工程から後工程に至るまで）、薬学・医療分野、他



エリプソ顕微鏡：

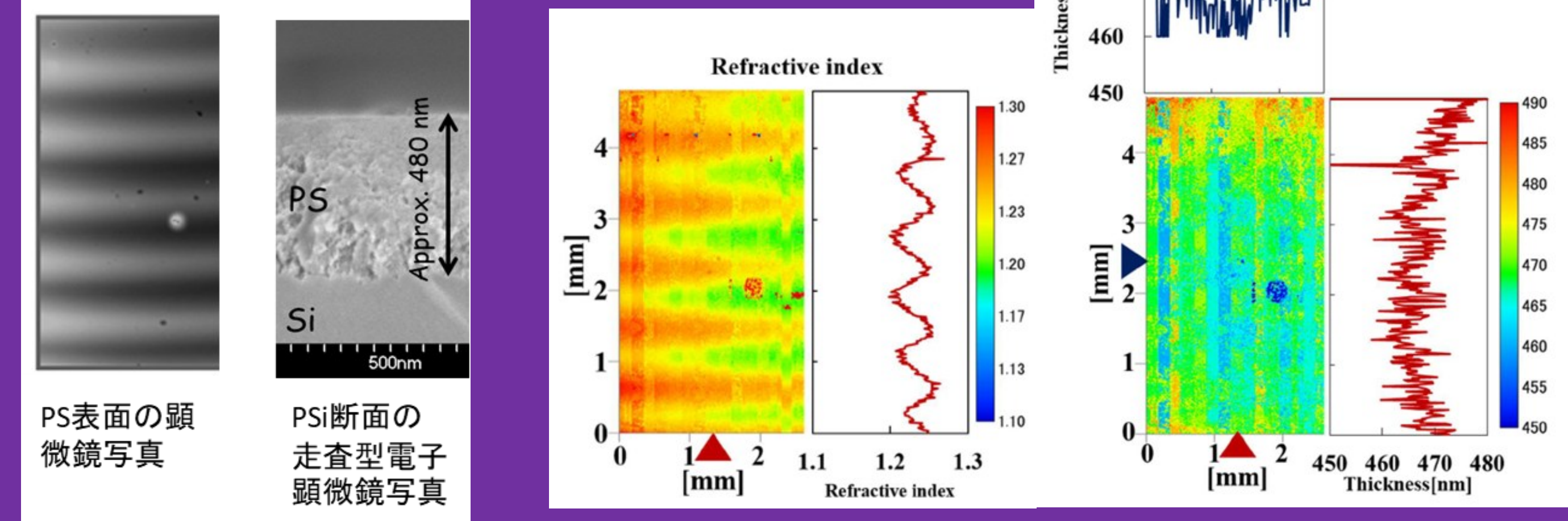


研究活動：

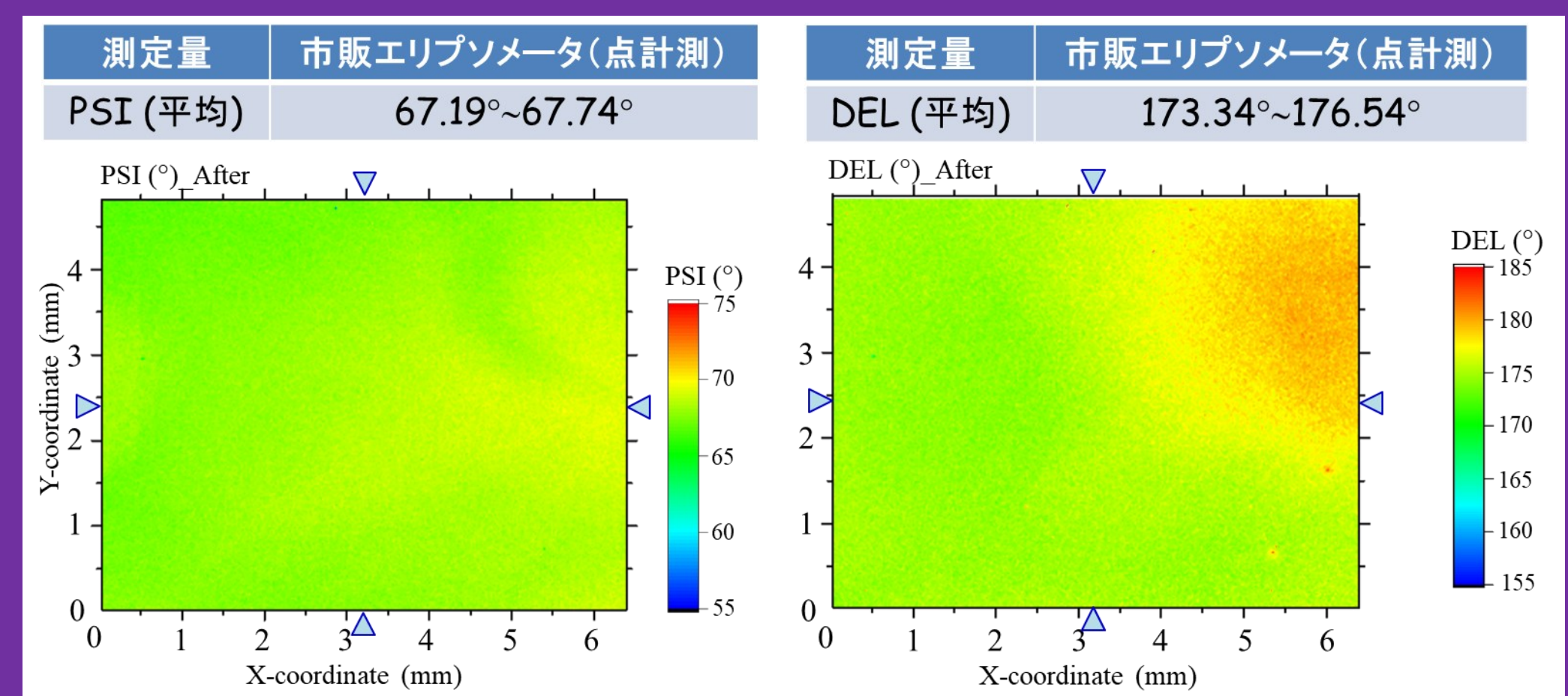


計測例：

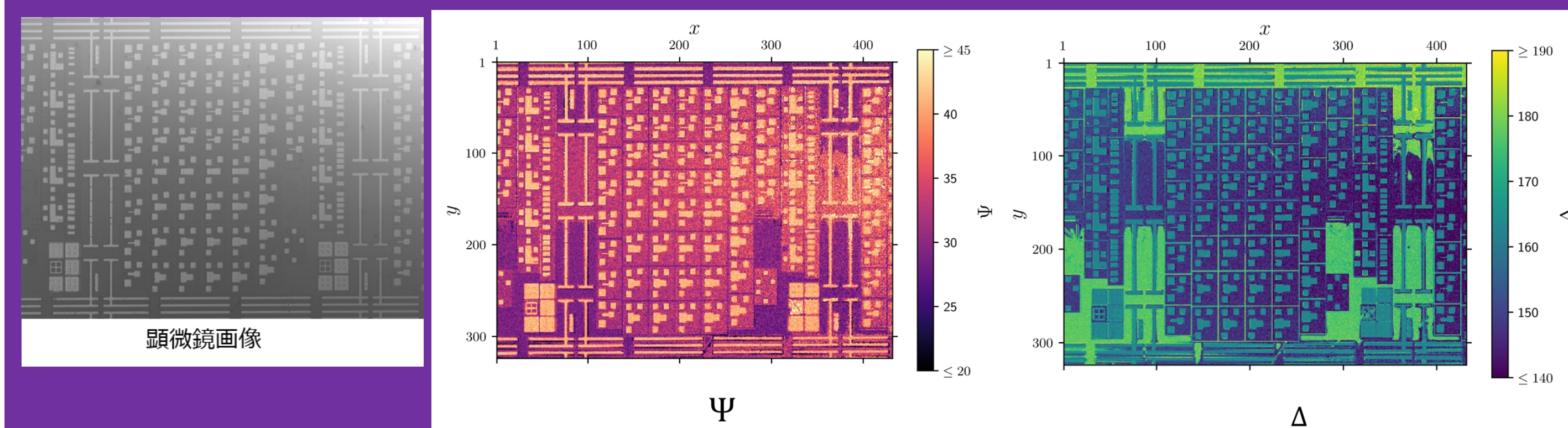
・ ポーラスシリコン層



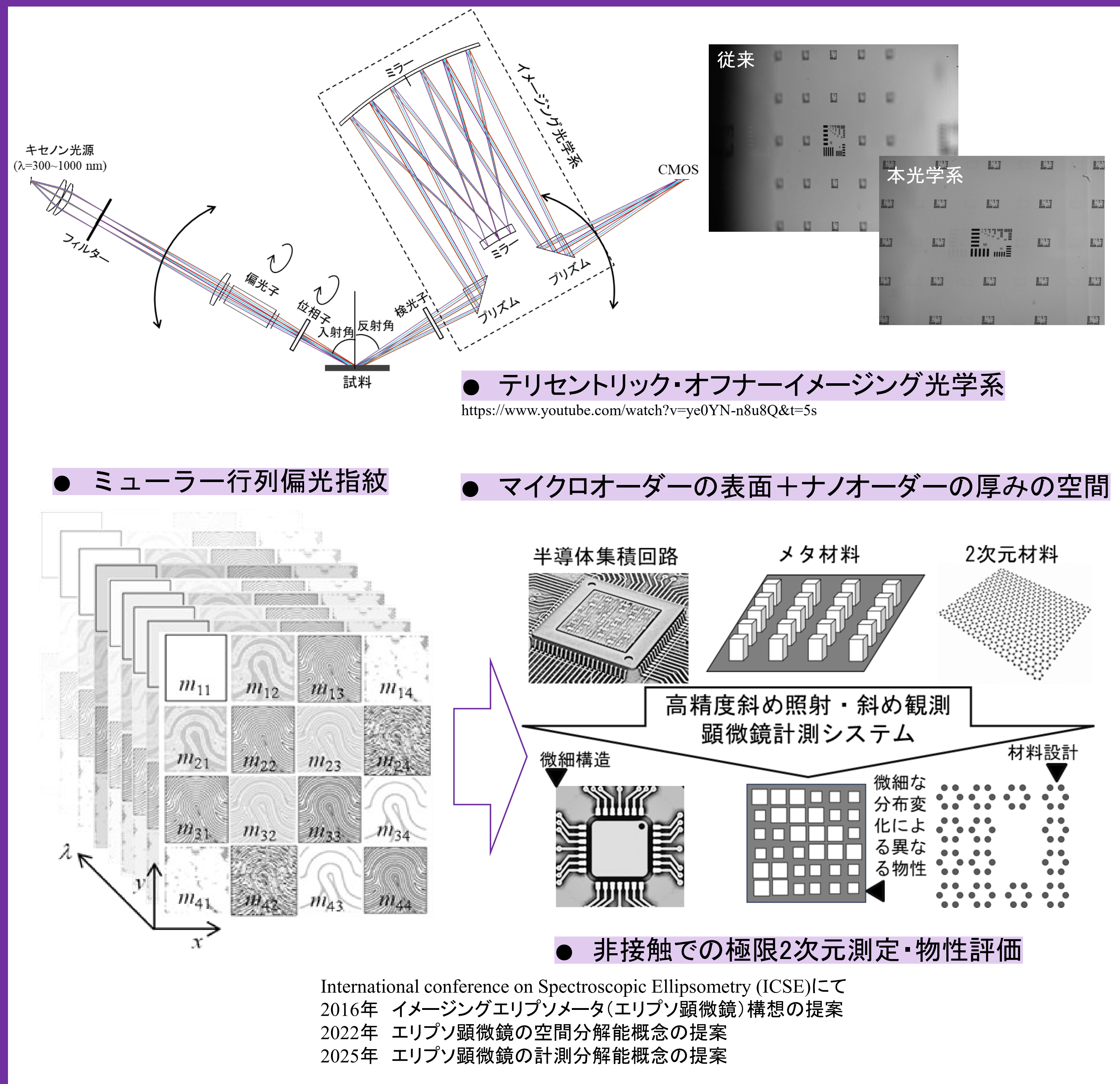
・ SiO₂/Si wafer



・ パターン



特徴：



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